

F. rm PTO-1449  
(Rev. 8-83)U.S. Department of Commerce  
Patent and Trademark Office

Atty Docket 0756-2401

Serial No. N/A

## INFORMATION DISCLOSURE STATEMENT

Applicants: Akira MASE

Filing Date: November 29, 2001

Group Art Unit:

## U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
<i>al</i>	3,079,282 ✓	02/01/1963	Haller et al.			
	3,621,564 ✓	11/01/1971	Tanaka et al.			
	3,822,467 ...	07/09/1974	Symersky			
	3,928,658 ✓	12/01/1975	van Boxtel et al.			
	3,983,284 ✓	09/01/1976	Croset			
	4,105,816 ✓	08/01/1978	Hori			
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	4,327,124 ✓	04/27/1982	DesMarais, Jr.			
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<i>a</i>	4,784,972 ✓	11/01/1988	Hatada			

## FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes No
<i>Ch</i>	0 154 443	09/11/1985	EP			Full Eng
<i>Ce</i>	2 032 127	04/30/1980	UK			Full Eng
<i>al</i>	2 064 233	06/01/1981	UK			Full Eng
<i>a</i>	2 160 693	12/01/1985	UK			Full Eng
<i>ce</i>	2 182 209	04/27/1973	FR			Conc Stmt
<i>ce</i>	2 525 209	10/21/1983	FR			Conc Stmt
<i>ce</i>	51-102466	09/09/1976	JP			Conc Stmt
<i>al</i>	53-092465	08/01/1978	JP			
<i>ce</i>	58-009124	01/19/1983	JP			Eng Abst
<i>ce</i>	58-148434	09/01/1983	JP			

Examiner

Date Considered

12/06/03

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

11/28/2001

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09/26/01

Form PTO-1449 (Rev. 8-83)		U.S. Department of Commerce Patent and Trademark Office		Atty Docket 0756-2401		Serial No. N/A	
<b>INFORMATION DISCLOSURE STATEMENT</b>				Applicants: Akira MASE			
				Filing Date: November 29, 2001		Group Art Unit: 1732	
<b>FOREIGN PATENT DOCUMENTS</b>							
Examiner. Initial	Document Number	Date	Country	Class	Subclass	Translation Yes      No	
a	60-092648	05/01/1985	JP				
ct	60-107845	06/13/1985	JP			Eng Abst	
a	60-108822	06/14/1985	JP			Eng Abst	
a	60-180151	09/01/1985	JP				
a	61-256657	11/14/1986	JP			Eng Abst	
<b>OTHER DOCUMENT</b> (Including Author, Title, Date, Pertinent Pages, Etc.)							
Examiner Initial							
a	IBM Technical Disclosure Bulletin, February 1966, Vol. 8, No. 9						
a	Mitchell et al., "Processing Techniques for Fabricating Thick Film Copper/Dielectric Multilayer Structures", pp. 1-10, May 14-16, 1979, IEEE 29th Electronic Components Conference ✓						
Examiner	Hoan Nguyen			Date Considered	12/06/03 5/23/03		
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